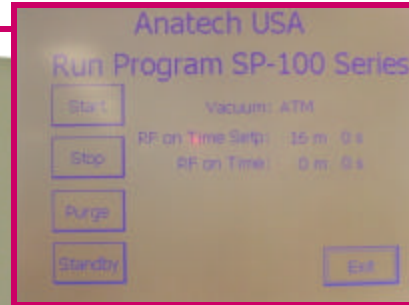


SCE-100 Series Plasma Systems



SCE-104 Shown with RF Matching Network



Siemens "Touch Panel" Control Password Protected



Inductively Coupled Plasma – ICP

SCE-104, 106 and SCE-108 Plasma Systems

"Ultra Clean" Quartz Chamber

There are no metal parts inside this chamber, your parts aren't exposed to the particulates associated with metal chambers.

Immersing parts in low temperature plasma may be your final cleaning solution !!

Anatech's plasma systems are CFC and effluent free, operator and environmentally safe, easily operated.

SCE 104, 106 and SCE 108 Plasma System Specifications

Control System

Siemens S7-200 series PLC controlled auto sequencing
Touch-Panel interface
On screen vacuum display –Pirani gauge
Gas flow control needle valve

Options:

Mass flow controller—up to 3-gasses
Multi-color touch screen
Multiple Process PLC with recipe and & process memory

Facility Requirements

115-VAC 20A 50/60-HZ Cabinet
115-VAC 20A 50/60-HZ Vacuum
60-PSI air
Process gas 5-8-PSI

Options:

220VAC option available

Quartz Reactor Chamber:

4" diameter x 8" long quartz chamber (104)
6" diameter x 8" long quartz chamber (106)
8" diameter x 8" long quartz chamber (108)
RF shielded
Front load
View port in door

Dimensions

23" W x 26" H x 30" D
150 Lbs. Crated weight (estimated)

RF Power Source

0-150 Watt RF 13.56 MHz supply
Manual tuning
Forward and reflected power readings

Options:

Low frequency
Automatic Tuning, matching network
0-300 Watt RF with auto tuner

Vacuum System

3.8 CFM Standard service pumping
KF-16 Pneumatic valve for pump isolation

Options:

Oxygen service Class "B" Preparation
Slow pump function to reduce turbulence during pump down

CALL ANATECH USA TODAY TO DISCUSS YOUR APPLICATION

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